

Docket No.: FUT-0104
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Masaaki Nagatsu

Application No.: 10/593,325

Confirmation No.: 8431

Filed: September 18, 2006

Art Unit: 1797

For: MICROWAVE PLASMA STERILIZING
METHOD AND DEVICE

Examiner: S. U. Kim

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT (IDS)

MS Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

This is to supplement Information Disclosure Statement (IDS) filed September 18, 2006. Attached is Japanese Patent Document (Cite No.11: JP-11-501530-A) submitted with the IDS of September 18, 2006. A copy of the PTO /SB/08a/b filed September 18, 2006 is attached hereto. Therefore, consideration and acknowledgement of the documents is respectfully requested.

Since this Supplemental Information Disclosure Statement is merely to supplement the Information Disclosure Statement of September 18, 2006, Applicant believes that no fee is required. However, please charge any fee deficiency or credit any overpayment to Deposit Account No. 18-0013 as needed to ensure consideration of the disclosed information.

Dated: September 29, 2009

Respectfully submitted,

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